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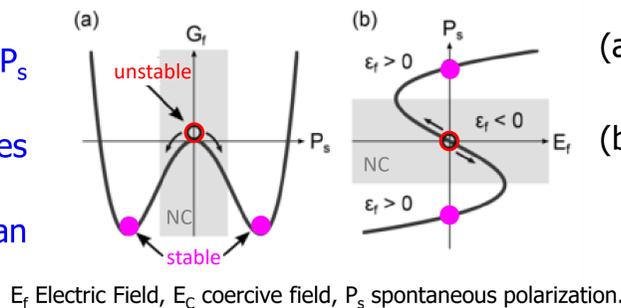
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The NegHEP Project

- ✓ The **INFN-CSN5 NegHEP** (NEGative capacitance field effect transistors for the future **High Energy Physics** applications) project proposes the use of innovative **Negative Capacitance** (NC) devices in particle detection systems for the next generation High Energy Physics (HEP) experiments at future colliders, featuring **self-amplified, segmented, high granularity sensors**.
- ✓ A **negative capacitor** in the gate stack of a FET can provide a step-up voltage, which can potentially overcome the fundamental limit in the subthreshold swing ($SS < 60\text{mV/dec}$), fostering the design of a single-transistor amplifier.
- ✓ The NC features of doped HfO_2 in **NC-FET** [1] is explored with advanced **TCAD** (Technology Computer Aided Design) modeling.
- ✓ An X-ray irradiation and characterization campaign has been set to assess the **NC-FET radiation hardness**.

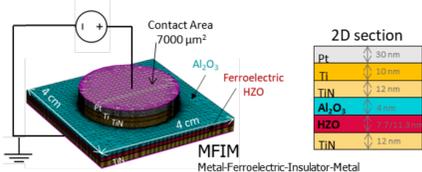
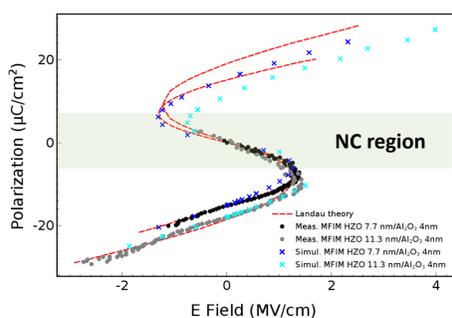
NC Working principle

- ✓ Ferroelectric materials show a polarization P_s even when E_f is not applied.
- ✓ In equilibrium, the ferroelectric material resides in one of the wells.
- ✓ P_s can be reversed by the application of an external E_f larger than E_c .



TCAD modeling of MFIM structures

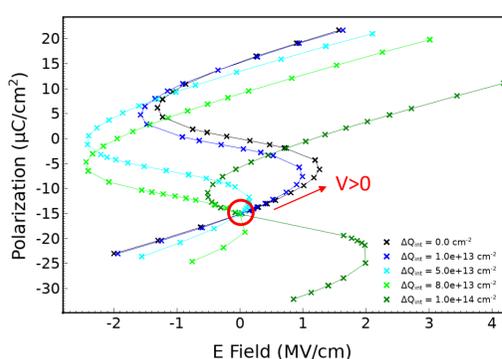
- ✓ Development of **ad-hoc material libraries** to describe the properties of the ferroelectric material HZO not included within the TCAD environment [3].
- ✓ **Ginzburg-Landau-Khalatnikov (GLK) equation**. The charge-boost NC phenomenon only takes place after proper capacitance matching between dielectric and ferroelectric materials [4].
- ✓ Pulsed Charge-Voltage (Q-V) measurements are necessary to access the ferroelectric NC region during switching by preventing charge injection.



Measured [5] and simulated Polarization- E_f curves for a MFIM structure 4 nm Al_2O_3 over HZO 7.7 and 11.3 nm. E_f is across the FE material. The **NC region** corresponds to the **negative slope** of the S-shaped Landau P-E curve.

Radiation Damage Effects

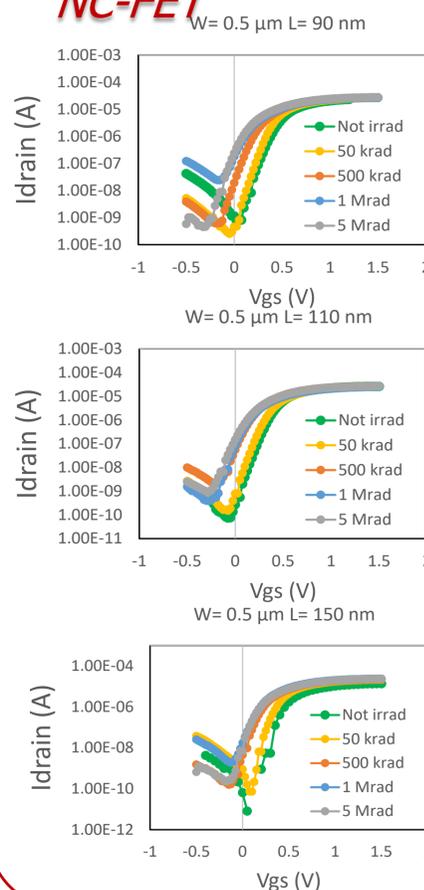
The overall Q_{int} can be accounted for as the sum of charge already present before irradiation $Q_{\text{int}}(0)$ and an additional positive fixed charge $\Delta Q_{\text{int}}(\phi)$ at the $\text{HZO}/\text{Al}_2\text{O}_3$ interface of increasing values, aiming at mimic increasing X-ray doses (ϕ).



Simulated P-E curves for a MFIM stack (4 nm Al_2O_3 over HZO 7.7 nm). **Surface damage effects** induced by X-rays have been accounted for with the parameter $\Delta Q_{\text{int}}(\phi)$ in the overall fixed oxide formula:

$$Q_{\text{int}}(\phi) = Q_{\text{int}}(0) + \Delta Q_{\text{int}}(\phi).$$

NC-FET



- ✓ Ultra-thin HfO_2 -based **n-channel NC-FETs** featuring different W/L characteristics. The gate length (L) ranges from 70 to 150 nm, while the width (W) is 0.25, 0.5, 1 and 5 μm .
- ✓ $I_{\text{ds}}-V_{\text{gs}}$ transfer characteristics for different W/L options.
- ✓ X-ray irradiation campaign at INFN Genova up to 5 Mrad.
- ✓ Method proposed by McWhorter: the effects of oxide charge and interface traps can be disentangled from the subthreshold-current curve of a MOSFET in saturation [6].

Conclusions

- ✓ Use of the TCAD modeling approach as a predictive tool to optimize the design and the operation of the new generation NC-FET devices for the future HEP in the HL-LHC scenario.
- ✓ The analysis and results obtained for MFIM capacitors can be straightforwardly extended to the study of NC-FETs.
- ✓ Irradiation and measurements campaign **ongoing** at INFN Genova and Perugia.
- ✓ In-depth investigation of radiation damage effects induced by irradiation on innovative NC-FETs.

References

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2. M. Hoffmann et al., APL Mater. 9, 020902 (2021).
3. A. Morozzi et al 2022 JINST 17 C01048.
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5. M. Hoffmann et al., 2018 IEEE International Electron Devices Meeting IEDM, 18-727 (2018).
6. McWhorter PJ, Winokur PS, Appl Phys Lett (1986) 48:133. doi:10.1063/1.96974.